

SENTINEL Scrubbers

True Protection From Hazardous Gases



System Description

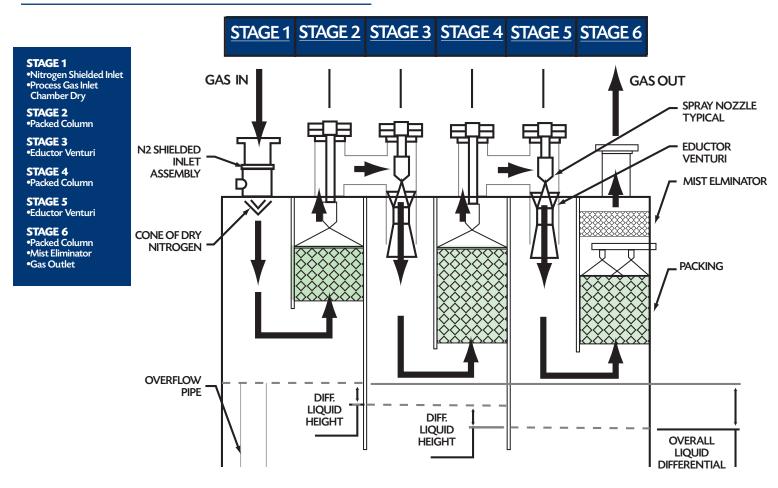
The Sentinel Series is a unique line of air pollution abatement devices specifically designed to treat semiconductor reactor effluent streams that contain highly corrosive, toxic or reactive gases. These point-of-use (POU) scrubbers are usually located as close to the process tool as possible, often in the sub-fab or cleanroom chase. These robust systems handle all water-soluble effluents from the process tool, including solids generating gases such as WF6, BCl3, and DCS.

Advantages

- Lowest cost of ownership
- SEMI S2 certified
- Reliable and easy to maintain
- Successfully treats F2
- N2 Shielded Inlet prevents water backstreaming to vacuum pump, keeps inlet clear
- Multiple chamber design hydrolyzes gases, removes both gases <u>and</u> particulates
- Extremely long gas residence time
- Removal efficiencies >99% on SiF4, DCS, WF6, HF, HCl, NH3 to name a few...
- Small footprint
- Integral 50 gallon sump
- Venturis induce gas flow and remove fine particles
- Zero pressure drop
- Liquids can be run in closed loop or continuous fashion
- Solid clear PVC construction
- Standalone and complete system integration capabilities

Typical Applications	Gases Treated	
Etch	DCS, TCS,	
CVD	BC13, WF6,	
Tungsten Dep.	SiF4, HF, HCl,	
RIE	F2, NH3, TEOS	
ILD		

ENVIRO-MATRIX Sentinel Series Scrubbers



Typical Equipment Package

- Sentinel Scrubber with easy access ports on inlet section, all packed column sections, and the sump
- System spray pump with TEFC motor and mechanical seal
- Non-fouling nitrogen shielded inlet with N2 regulator
- Adjustable, fresh water flowmeter
- · Heavy duty modular frame
- High efficiency mist eliminator
- NEMA 4X control panel with PLC
- Scrubber housing, heavy duty clear PVC. All wetted parts are corrosion resistant.

Optional Equipment

- NEMA 4X control with EMO/Estop with PLC
- Splash guards/spill trays
- Remote diagnostics
- High level alarms
- Pressure monitors
- High temperature thermoplastics
- pH/ORP
- · Chemical addition
- Custom designs

Operating Parameters

Gas Capacity

Gas Residence Time

Spray Rate

Total Gas Flow: 300 lpm

45 sec @ 300 lpm

30 gpm @ 30 psig

Fresh Water Feed 1/8 - 1 gpm (variable with location and application)

Scrubber Sump Capacity 50 gallon

Power Requirements

Equipment Weights

Spray Pump 2 HP Scrubber/Skid-Dry Approx. 350 lbs Scrubber/Skid-Operating Approx. 775 lbs

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